

Venue	Room	2019/12/10					2019/12/11				2019/12/12					2019/12/13				
Time	-	7 : 00-10 : 00	10 : 20-12 : 00	12 : 50-14 : 30	14 : 50-16 : 30	17 : 00-19 : 00	7 : 00-10 : 00	10 : 20-12 : 00	12 : 50-14 : 30	15:10-16:50	7 : 00-10 : 00	10 : 20-12 : 00	12 : 50-14 : 30	15:10-16:50	17 : 00-19 : 00	7 : 00-10 : 00	10 : 20-12 : 00	12 : 50-14 : 30	15:10-16:50	
SEMI Japan	Room 1	13-15 Gases & Facilities joint TC 15:30-18:00 JRSC 10-17 Test Method TF 13-17 DDA TF																		
	Room 2																			
	Room 3																			
	Room 4																			
Tokyo Big Sight Conference Tower 6F&7F	701(80) Conference Room						09-12 International Test Method TF		13-14 ASI TF		8:30-11:30 ISC (Invitation)		13:15-14:45 RF Measurement TF		15:00-17:30 Metrics TC		09:00-10:30 Traceability TC		13-16 EHS TC	
	702(80) Conference Room	10:00-10:30 Liquid Filter TF, 10:30-12:00 Trace Metal Analysis for High Pure IPA TF					10-12 Liquid Filter TF/IPA TF		13:30-15:30 LC TC		09-12 AWG TF		12-13 SiW GCS	13-17 Silicon Wafer TC		10-12 DDA TF (Discussion Session)		13-17 I&C TC		
	703(150) Conference Room						09-12 PLP Panel FOUP TF		14-16 PI&C TC		09-12 Fab & Equipment Information Security TF		13:30-16:30 GEM300 TF						13-14 Tape Frame Loader	14-16 300mm Tape Frame PI&C TF
	609(190) Conference Room								13-17 DDA TF		09-11 EMT & SDT				15-17 Sensor Bus TF					
TechSTA GE枠	607(190) Conference Room	Standards related program and Network event					10:20-12:00 3DP&I Workshop						12:50-14:30 Traceability Workshop							
TechSTA GE枠	608(190) Conference Room								15:30-16:50 Smart Manufacturing Forum		10:20-12:00 持続可能な先端ファブフォーラム		12:50-14:30 BCPセミナー							
													12:00-12:50 (?) BCP Lunch		17:30-19:00 FS Party					